



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Confirmation No. 2337**  
Hiroshi TAKENO : Attorney Docket No. 2004\_1129A  
Serial No. 10/501,672 : Group Art Unit 1722  
Filed July 16, 2004 : Examiner Felisa C. Hiteshew  
SILICON EPITAXIAL WAFER AND : **Mail Stop: Amendment**  
PROCESS FOR MANUFACTURING  
THE SAME

**AMENDMENT**

THE COMMISSIONER IS AUTHORIZED  
TO CHARGE ANY DEFICIENCY IN THE  
FEE FOR THIS PAPER TO DEPOSIT  
ACCOUNT NO. 23-0975.

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Responsive to the Official Action dated July 27, 2006, the time for responding thereto being extended for three months in accordance with a petition for extension submitted concurrently herewith, please amend the above-identified application as follows: